

FEI Tecnai Osiris 200kV S/TEM

- Super-X EDX detection system, SDD technology, windowless, shutter-protected, X-FEG Electron Source
- TEM resolution: point 0.25 nm, line 0.102 nm, extended 0.16 nm with TrueImage™ software, STEM HAADF 0.18 nm
- EFTEM with EELS and Gatan Orius CCD

